

CONTENTS

<i>Contributors</i>	xii
<i>Preface</i>	xiii
<i>Future Contributions</i>	xvii
PART 1: Historical background	1
1. History of Direct Aberration Correction	3
Harald Rose	
I. Introduction	3
II. Birth of Aberration Correction	5
III. Other Early Correction Efforts	9
IV. The Darmstadt Correction Project	12
V. The Chicago and EMBL Quadrupole-Octopole Probe Correctors	18
VI. Evolution of the Hexapole Corrector	19
VII. Aberration Correction of Systems with Curved Axis	25
VIII. Revival of the Quadrupole-Octopole Corrector	29
IX. Conclusion and Outlook	34
Acknowledgments	36
References	36
PART 2: Aberration corrector design	41
2. Present and Future Hexapole Aberration Correctors for High-Resolution Electron Microscopy	43
Maximilian Haider, Heiko Müller, and Stephan Uhlemann	
I. Introduction	44
II. Present Hexapole Correctors	70
III. Hexapole Aplanats	101
IV. Conclusion	114
Acknowledgments	116
References	117

3. Advances in Aberration-Corrected Scanning Transmission Electron Microscopy and Electron Energy-Loss Spectroscopy	121
Ondrej L. Krivanek, Niklas Dellby, Robert J. Keyse, Matthew F. Murfitt, Christopher S. Own, and Zoltan S. Szilagyi	
I. Introduction	121
II. Aberration Correction by Non-Round Lenses	124
III. Performance of Aberration-Corrected Instruments	129
IV. New Applications	140
V. Conclusions	154
Acknowledgments	155
References	155
PART 3: Results obtained with aberration-corrected instruments	161
4. First Results Using the Nion Third-Order Scanning Transmission Electron Microscope Corrector	163
P. E. Batson	
I. Introduction	163
II. The IBM High-Resolution STEM/EELS System	164
III. First Results	168
IV. Calculation of Probe Properties	174
V. Imaging of Crystalline Objects	176
VI. AlN/GaN/AlN Quantum Well Structure	179
VII. Hafnium Oxide Gate Stack	183
VIII. Multislice Simulations	187
IX. Atomic Movement Under the Electron Beam	190
X. Conclusions	192
Acknowledgments	193
References	193
5. Scanning Transmission Electron Microscopy and Electron Energy Loss Spectroscopy: Mapping Materials Atom by Atom	195
Andrew L. Bleloch	
I. Introduction	195
II. Experimental Heuristics	196

III. Case Studies	199
IV. Discussion	221
References	221
6. Aberration Correction With the SACTEM-Toulouse: From Imaging to Diffraction	225
Florent Houdellier, Martin Hÿtch, Florian Hüe, and Etienne Snoeck	
I. Introduction	225
II. Aberration Correction and Strain Mapping	232
III. Aberration-Corrected Convergent-Beam Electron Holography	240
IV. Aberration-Corrected Electron Diffraction	245
V. Pseudo-Lorentz Mode for Medium-Resolution Electron Holography	252
VI. Conclusions	256
Acknowledgments	256
References	256
7. Novel Aberration Correction Concepts	261
Bernd Kabius and Harald Rose	
I. Introduction	261
II. Concepts for Improving Resolution for In Situ TEM	262
III. C_c Correction	265
IV. Summary	279
Acknowledgments	280
References	280
8. Aberration-Corrected Imaging in Conventional Transmission Electron Microscopy and Scanning Transmission Electron Microscopy	283
Angus I. Kirkland, Peter D. Nellist, Lan-Yun Chang, and Sarah J. Haigh	
I. Introduction	284
II. The Wave Aberration Function	286
III. Coherence Effects in CTEM and STEM	297
IV. Aberration-Correction Imaging Conditions	308
V. Conclusions	319
Acknowledgments	320
References	320

9. Materials Applications of Aberration-Corrected Scanning Transmission Electron Microscopy	327
S. J. Pennycook, M. F. Chisholm, A. R. Lupini, M. Varela, K. van Benthem, A. Y. Borisevich, M. P. Oxley, W. Luo, and S. T. Pantelides	
I. Introduction	327
II. Key Instrumental Advances	328
III. Measurement and Definition of Resolution	348
IV. Complex Oxides: Manganites	355
V. High-Temperature Superconductors	361
VI. Complex Dislocation Core Structures	363
VII. Understanding Structure-Property Relations in Ceramics	367
VIII. Semiconductor Quantum Wires	371
IX. Catalysts	374
X. Future Directions	377
Acknowledgments	378
References	378
10. Spherical Aberration-Corrected Transmission Electron Microscopy for Nanomaterials	385
Nobuo Tanaka	
I. Introduction	386
II. Imaging Theories of HRTEM Using Aberration Correctors	387
III. Actual Advantages for Observation by C_s -Corrected TEM	406
IV. Actual Advantages for Observation by C_s -Corrected STEM	424
V. Three-Dimensional Observation of Atomic Objects in C_s -Corrected STEM	430
VI. Conclusion and Future Prospects	433
Acknowledgments	434
References	434
11. Atomic-Resolution Aberration-Corrected Transmission Electron Microscopy	439
Knut Urban, Lothar Houben, Chun-Lin Jia, Markus Lentzen, Shao-Bo Mi, Andreas Thust, and Karsten Tillmann	
I. Introduction	440
II. Fundamentals of Atomic-Resolution Imaging in a Transmission Electron Microscope	440
III. Atomic-Resolution Electron Microscopy and the Inversion of the Scattering and Imaging Problem	450

IV. Selected Materials Science Applications	457
V. Conclusions	477
References	478
12. Aberration-Corrected Electron Microscopes at Brookhaven National Laboratory	481
Yimei Zhu and Joe Wall	
I. Introduction	481
II. Environmental Requirements and Laboratory Design for Aberration-Corrected Electron Microscopes	483
III. The BNL Aberration-Corrected Instruments	492
IV. A Brief Comparison of the Three Instruments	507
V. Evaluation and Applications of STEM	510
VI. Outlook	520
Acknowledgments	521
References	521
Contents of Volumes 151 and 152	525
Index	527
Color Plate Section	